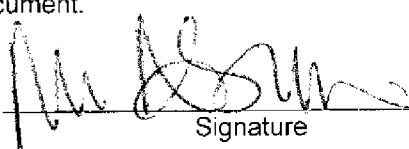


Client Code: QCO.000GEN

**RECORDATION FORM COVER SHEET  
PATENTS ONLY**

To the Director, U.S. Patent and Trademark Office: Please record the attached original documents or copy thereof.

1. Name of conveying party: QUALCOMM MEMS Technologies, Inc. Additional name(s) of conveying party(ies) attached? ( ) Yes (X) No	2. Name and address of receiving party: <b>Name:</b> QUALCOMM Incorporated <b>Internal Address:</b> <b>Street Address:</b> 5775 Morehouse Drive <b>City:</b> San Diego <b>State:</b> CA <b>ZIP:</b> 92121 Additional names of receiving parties attached? ( ) Yes (X) No
3. Nature of conveyance: (X) Assignment ( ) Security Agreement ( ) Merger ( ) Change of Name ( ) Other: Execution Date: May 23, 2007 and June 1, 2007	4. US or PCT Application number or US Patent number: Patent Application No.: (Per Attached List) Filing Date: Additional numbers attached? (Per Attached List)
5. Party to whom correspondence concerning document should be mailed: <b>Customer No.</b> 59,747 <b>Address:</b> Knobbe, Martens, Olson & Bear, LLP 2040 Main Street, 14 <sup>th</sup> Floor Irvine, CA 92614 <b>Return Fax:</b> (949) 760-9502 <b>Attorney's Docket No.:</b> QCO.000GEN	6. Total number of applications and patents involved: 115
7. Total fee (37 CFR 1.21(h)): \$4,600 (X) Authorized to be charged to deposit account	8. Deposit account number: 11-1410 Please charge this account for any additional fees which may be required, or credit any overpayment to this account.
9. Statement and signature. To the best of my knowledge and belief, the foregoing information is true and correct, and any attached copy is a true copy of the original document.  <div style="display: flex; justify-content: space-between;"> <div style="width: 30%;"> <u>Mark M. Abumeri</u>  Name of Person Signing    43,458  Registration No. </div> <div style="width: 30%; text-align: center;">   Signature </div> <div style="width: 30%; text-align: center;"> <u>June 27, 2007</u>  Date </div> </div> Total number of pages including cover sheet, attachments and document: 9	

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**EXHIBIT A****Assignment from QUALCOMM MEMS Technologies, Inc. to QUALCOMM Incorporated**

<b>Application No.</b>	<b>Filing Date:</b>	<b>Title of Invention:</b>	<b>KMOB Ref.</b>	<b>QMT Ref:</b>
11/367098	3/2/2006	METHODS FOR PRODUCING MEMS WITH PROTECTIVE COATINGS USING MULTI-COMPONENT SACRIFICIAL LAYERS	QCO.017A	050279
11/145416	6/3/2005	INTERFEROMETRIC MODULATOR WITH INTERNAL POLARIZATION AND DRIVE METHOD	QCO.021A	050351
11/413239	4/28/2006	SYSTEM AND METHOD OF DRIVING A MEMS DISPLAY DEVICE	QCO.029A	050535
60/678361	5/5/2005	SYSTEM AND METHOD FOR DRIVING A MEMS DISPLAY DEVICE	QCO.029PR	050535P1
11/429571	5/5/2006	DYNAMIC DRIVER IC AND DISPLAY PANEL CONFIGURATION	QCO.030A	050653
60/678482	5/5/2005	DYNAMIC DRIVER IC AND DISPLAY PANEL CONFIGURATION	QCO.030PR	050653P1
11/404449	4/14/2006	SYSTEMS AND METHODS OF ACTUATING MEMS DISPLAY ELEMENTS	QCO.031A	050386
60/678473	5/5/2005	SYSTEM AND METHOD FOR DRIVING A MEMS DISPLAY DEVICE	QCO.031PR	050386P1
11/490880	7/21/2006	MEMS DEVICES HAVING OVERLYING SUPPORT STRUCTURES AND METHODS OF FABRICATING THE SAME	QCO.032A1	050851U1
11/491490	7/21/2006	MEMS DEVICES HAVING SUPPORT STRUCTURES AND METHODS OF FABRICATING THE SAME	QCO.032A2	050851U2
60/701655	7/22/2005	METHOD OF FABRICATING AN INTERFEROMETRIC MODULATOR COMPRISING RIGID SUPPORT STRUCTURES	QCO.032PR	050851P1
11/491389	7/21/2006	SUPPORT STRUCTURE FOR MEMS DEVICE AND METHODS THEREFOR	QCO.033A	051008
60/702080	7/22/2005	SUPPORT STRUCTURE FOR MEMS DEVICE	QCO.033PR	051008P1
11/506770	8/18/2006	METHODS FOR ETCHING LAYERS WITHIN A MEMS DEVICE TO ACHIEVE A TAPERED EDGE	QCO.034A1	050941U1
11/506622	8/18/2006	METHODS FOR FORMING LAYERS WITHIN A MEMS DEVICE USING LIFTOFF PROCESSES TO ACHIEVE A TAPERED EDGE	QCO.034A2	050941U2
11/506600	8/18/2006	MEMS DEVICES HAVING SUPPORT STRUCTURES WITH SUBSTANTIALLY VERTICAL SIDEWALLS AND METHODS FOR FABRICATING THE SAME	QCO.034A3	050941U3
11/506594	8/18/2006	MEMS DEVICE HAVING SUPPORT STRUCTURES CONFIGURED TO MINIMIZE STRESS-RELATED DEFORMATION AND METHODS FOR FABRICATING SAME	QCO.034A4	050941U4

## EXHIBIT A

## Assignment from QUALCOMM MEMS Technologies, Inc. to QUALCOMM Incorporated

60/710019	8/19/2005	SUPPORT STRUCTURES FOR MEMS DEVICES AND METHODS FOR FORMING THE SAME	QCO.034PR	050941P1
11/540485	9/29/2006	MEMS DEVICE AND INTERCONNECTS FOR SAME	QCO.035A	051355
60/723540	9/30/2005	MEMS DEVICE HAVING INTERCONNECTS FORMED OF SACRIFICIAL MATERIAL	QCO.035PR	051355P1
60/718920	9/20/2005	ETCHING SYSTEM AND METHOD	QCO.037PR	050377P1
11/321134	12/29/2005	METHOD OF CREATING MEMS DEVICE CAVITIES BY A NON-ETCHING PROCESS	QCO.039A	050838
11/334990	1/18/2006	SILICON-RICH SILICON NITRIDES AS ETCH STOPS IN MEMS MANUFACTURE	QCO.040A	050987
11/360131	2/22/2006	ELECTRICAL CONDITIONING OF MEMS DEVICE AND INSULATING LAYER THEREOF	QCO.041A	051184
11/405116	4/17/2006	MODE INDICATOR FOR INTERFEROMETRIC MODULATOR DISPLAYS	QCO.043A	050188
11/673330	2/9/2007	METHOD AND SYSTEM FOR UPDATING OF DISPLAYS SHOWING DETERMINISTIC CONTENT	QCO.044A	050370
60/772613	2/10/2006	METHOD AND SYSTEM FOR UPDATING OF DISPLAYS SHOWING DETERMINISTIC CONTENT	QCO.044PR	050370P1
11/331705	1/13/2006	INTERCONNECT STRUCTURE FOR MEMS DEVICE	QCO.045A	050702
11/317421	12/22/2005	SYSTEM AND METHOD FOR POWER REDUCTION WHEN DECOMPRESSING VIDEO STREAMS FOR INTERFEROMETRIC MODULATOR DISPLAYS	QCO.046A	050576
11/296656	12/7/2005	METHOD AND SYSTEM FOR WRITING DATA TO MEMS DISPLAY ELEMENTS	QCO.048A	060012
11/401023	4/10/2006	INTERFEROMETRIC OPTICAL DISPLAY SYSTEM WITH BROADBAND CHARACTERISTICS	QCO.049A	051229
11/406776	4/19/2006	NON-PLANAR SURFACE STRUCTURES AND PROCESS FOR MICROELECTROMECHANICAL SYSTEMS	QCO.050A	051264
11/406981	4/19/2006	NON-PLANAR SURFACE STRUCTURES AND PROCESS FOR MICROELECTROMECHANICAL SYSTEMS	QCO.051A	051308
11/406866	4/19/2006	NON-PLANAR SURFACE STRUCTURES AND PROCESS FOR MICROELECTROMECHANICAL SYSTEMS	QCO.052A	051324
11/360162	2/23/2006	MEMS DEVICE HAVING A LAYER MOVABLE AT ASYMMETRIC RATES	QCO.053A	050618

## EXHIBIT A

Assignment from QUALCOMM MEMS Technologies, Inc. to QUALCOMM Incorporated

11/439012	5/22/2006	BACK-TO-BACK DISPLAYS	QCO.054A	050427
11/358997	2/21/2006	METHOD FOR PROVIDING AND REMOVING DISCHARGING INTERCONNECT FOR CHIP-ON GLASS OUTPUT LEADS AND STRUCTURES THEREOF	QCO.055A	050730
11/479865	6/29/2006	PASSIVE CIRCUITS FOR DE-MULTIPLEXING DISPLAY INPUTS	QCO.056A	051326
11/647822	12/29/2006	SWITCHES FOR SHORTING DURING MEMS ETCH RELEASE	QCO.057A	050857U1
11/648244	12/29/2006	PERIPHERAL SWITCHES FOR MEMS DISPLAY TEST	QCO.057A2	050857U2
11/656681	1/23/2007	MEMS DEVICE WITH INTEGRATED OPTICAL ELEMENT	QCO.058A	060187
60/762723	1/27/2006	MEMS DEVICE WITH INTEGRATED OPTICAL ELEMENT	QCO.058PR	060187P1
11/453633	6/15/2006	SYSTEM AND METHOD FOR PROVIDING RESIDUAL STRESS TEST STRUCTURES	QCO.059A	060216
60/757048	1/6/2006	SYSTEM AND METHOD FOR PROVIDING RESIDUAL STRESS TEST STRUCTURES	QCO.059PR	060216P1
11/407730	4/19/2006	MICROELECTROMECHANICAL DEVICE AND METHOD UTILIZING NANOPARTICLES	QCO.060A	060004
11/407470	4/19/2006	MICROELECTROMECHANICAL DEVICE AND METHOD UTILIZING A POROUS SURFACE	QCO.061A	060032
11/445529	6/1/2006	PATTERNING OF MECHANICAL LAYER IN MEMS TO REDUCE STRESSES AT SUPPORTS	QCO.062A	050985
11/416920	5/3/2006	ELECTRODE AND INTERCONNECT MATERIALS FOR MEMS DEVICES	QCO.063A	060024
11/445607	6/1/2006	PROCESS AND STRUCTURE FOR FABRICATION OF MEMS DEVICE HAVING ISOLATED EDGE POSTS	QCO.064A	060141
11/591809	11/2/2006	COMPATIBLE MEMS SWITCH ARCHITECTURE	QCO.065A	050424
11/454162	6/15/2006	METHOD AND APPARATUS FOR LOW RANGE BIT DEPTH ENHANCEMENT FOR MEMS DISPLAY ARCHITECTURES	QCO.066A	050946
11/595621	11/9/2006	TWO PRIMARY COLOR DISPLAY	QCO.067A	050648
11/472880	6/21/2006	SYSTEMS AND METHODS FOR DRIVING MEMS DISPLAY	QCO.068A	050340
11/478702	6/30/2006	METHOD OF MANUFACTURING MEMS DEVICES PROVIDING AIR GAP CONTROL	QCO.069A	051222
11/841649	12/19/2006	MEMS SWITCHES WITH DEFORMING MEMBRANES	QCO.070A	060209
11/504319	8/15/2006	HIGH PROFILE CONTACTS FOR MICROELECTROMECHANICAL SYSTEMS	QCO.071A	050855

## EXHIBIT A

## Assignment from QUALCOMM MEMS Technologies, Inc. to QUALCOMM Incorporated

11/476317	6/28/2006	SUPPORT STRUCTURE FOR FREE-STANDING MEMS DEVICE AND METHODS FOR FORMING THE SAME	QCO.072A	060310U1
11/476998	6/28/2006	SUPPORT STRUCTURE FOR FREE-STANDING MEMS DEVICES AND METHODS FOR FORMING THE SAME	QCO.072A2	060310U2
10/249061	3/13/2003	OPTICAL INTERFERENCE TYPE PANEL AND THE MANUFACTURING METHOD THEREOF	QCO.073A	061102
10/249243	3/26/2003	OPTICAL INTERFERENCE TYPE OF COLOR DISPLAY HAVING OPTICAL DIFFUSION LAYER BETWEEN SUBSTRATE AND ELECTRODE	QCO.074A	061103
10/711665	9/30/2004	OPTICAL INTERFERENCE TYPE OF COLOR DISPLAY	QCO.074DV1	061103D1
10/249244	3/26/2003	OPTICAL INTERFERENCE COLOR DISPLAY AND OPTICAL INTERFERENCE MODULATOR	QCO.075A	061104
10/670734	9/26/2003	COLOR CHANGEABLE PIXEL	QCO.076A	061109
10/901163	7/29/2004	COLOR CHANGEABLE PIXEL	QCO.076DV1	061109D1
10/670737	9/26/2003	STRUCTURE OF A LIGHT-INCIDENCE ELECTRODE OF AN OPTICAL INTERFERENCE DISPLAY PLATE	QCO.077A	061110
10/705824	11/13/2003	METHOD FOR FABRICATING AN INTERFERENCE DISPLAY UNIT	QCO.078A	061106
10/713508	11/14/2003	METHOD FOR FABRICATING AN INTERFERENCE DISPLAY UNIT	QCO.079A	061108
10/706923	11/14/2003	INTERFERENCE DISPLAY UNIT	QCO.080A	061107
11/069938	3/3/2005	METHOD FOR FABRICATING AN INTERFERENCE DISPLAY UNIT	QCO.080DV1	061107D1
10/725585	12/3/2003	STRUCTURE OF A STRUCTURE RELEASE AND A METHOD FOR MANUFACTURING THE SAME	QCO.081A	061111
10/742062	12/20/2003	STRUCTURE OF AN OPTICAL INTERFERENCE DISPLAY CELL	QCO.082A	061105
10/752666	1/8/2004	OPTICAL-INTERFERENCE TYPE DISPLAY PANEL AND METHOD FOR MAKING THE SAME	QCO.083A	061100
10/752811	1/8/2004	OPTICAL-INTERFERENCE TYPE REFLECTIVE PANEL AND METHOD FOR MAKING THE SAME	QCO.084A	061101
11/261466	10/31/2005	METHOD FOR MAKING AN OPTICAL INTERFERENCE TYPE REFLECTIVE PANEL	QCO.084DV1	061101D1
10/796997	3/11/2004	METHOD FOR FABRICATING OPTICAL INTERFERENCE DISPLAY CELL	QCO.085A	061112
11/413603	4/28/2006	OPTICAL INTERFERENCE DISPLAY CELL AND METHOD OF MAKING THE SAME	QCO.085C1	061112C1
10/807128	3/24/2004	OPTICAL INTERFERENCE DISPLAY PANEL AND MANUFACTURING METHOD THEREOF	QCO.086A	061118

## EXHIBIT A

## Assignment from QUALCOMM MEMS Technologies, Inc. to QUALCOMM Incorporated

10/807129	3/24/2004	AN INTERFERENCE DISPLAY CELL	QCO.087A	061119
11/221806	9/9/2005	INTERFERENCE DISPLAY CELL AND FABRICATION METHOD THEREOF	QCO.087DV1	061119D1
10/807142	3/24/2004	OPTICAL INTERFERENCE DISPLAY PANEL	QCO.088A	061117
10/807143	3/24/2004	STRUCTURE OF AN OPTICAL INTERFERENCE DISPLAY UNIT	QCO.089A	061122
10/807147	3/24/2004	OPTICAL INTERFERENCE DISPLAY PANEL	QCO.090A	061116
11/368683	3/7/2006	OPTICAL INTERFERENCE DISPLAY PANEL	QCO.090DV1	061116D1
10/810660	3/29/2004	STRUCTURE OF A MICRO ELECTRO MECHANICAL SYSTEM AND THE MANUFACTURING METHOD THEREOF	QCO.091A	061121
10/812257	3/29/2004	MICRO ELECTRO MECHANICAL SYSTEM DISPLAY CELL AND METHOD FOR FABRICATING THEREOF	QCO.092A	061124
10/815884	3/31/2004	COLOR-CHANGEABLE PIXELS OF AN OPTICAL INTERFERENCE DISPLAY PANEL	QCO.093A	061115
10/815905	3/31/2004	INTERFEROMETRIC MODULATION PIXELS AND MANUFACTURING METHOD THEREOF	QCO.094A	061113
10/815947	4/2/2004	INTERFEROMETRIC MODULATION PIXELS AND MANUFACTURING METHOD THEREOF	QCO.095A	061114
10/873014	6/21/2004	OPTICAL INTERFERENCE REFLECTIVE ELEMENT AND REPAIRING AND MANUFACTURING METHODS THEREOF	QCO.096A	061120
10/884555	7/2/2004	INTERFERENCE DISPLAY PLATE AND MANUFACTURING METHOD THEREOF	QCO.097A	061123
10/960927	10/12/2004	STRUCTURE OF A MICRO ELECTRO MECHANICAL SYSTEM	QCO.098A	061126
11/133641	5/20/2005	METHOD OF MANUFACTURING OPTICAL INTERFERENCE COLOR DISPLAY	QCO.099A	061125
11/491047	7/21/2006	SUPPORT STRUCTURE FOR MEMS DEVICE AND METHODS THEREFOR	QCO.105A	050671
11/497726	8/2/2006	SELECTIVE ETCHING OF MEMS USING GASEOUS HALIDES AND REACTIVE CO-ETCHANTS	QCO.107A	060418
11/583575	10/19/2006	SACRIFICIAL SPACER PROCESS AND RESULTANT STRUCTURE FOR MEMS SUPPORT STRUCTURE	QCO.108A	060836
11/699542	1/29/2007	HYBRID COLOR SYNTHESIS FOR MULTISTATE REFLECTIVE INTERFEROMETRIC MODULAR DISPLAYS	QCO.109A	060717
11/467879	8/28/2006	ANGLE SWEEPING HOLOGRAPHIC ILLUMINATOR	QCO.111A	060289
60/791730	4/13/2006	MEMS DEVICES AND PROCESSES FOR PACKAGING SUCH DEVICES	QCO.112PR	060132P1

## EXHIBIT A

## Assignment from QUALCOMM MEMS Technologies, Inc. to QUALCOMM Incorporated

11/479392	6/30/2006	DETERMINATION OF INTERFEROMETRIC MODULATOR MIRROR CURVATURE AND AIRGAP VARIATION USING DIGITAL PHOTOGRAPHS	QCO.113A	060907
11/704450	2/8/2007	PASSIVE CIRCUITS FOR DE-MULTIPLEXING DISPLAY INPUTS	QCO.116A	061329
11/698609	1/25/2007	ARBITRARY POWER FUNCTION USING LOGARITHM LOOKUP TABLE	QCO.117A	060757
60/815905	6/21/2006	MEMS DEVICE HAVING A RECESSED CAVITY AND METHODS THEREFOR	QCO.120PR	061384P1
11/566172	12/1/2006	IMPROVED MEMS PROCESSING	QCO.121A	060989
11/614795	12/21/2006	METHOD AND APPARATUS FOR MEASURING THE FORCE OF STICTION OF A MEMBRANE IN A MEMS DEVICE	QCO.122A	051075
11/544978	10/6/2006	INTERNAL OPTICAL ISOLATION STRUCTURE FOR INTEGRATED FRONT OR BACK LIGHTING	QCO.123A	051269
11/545104	10/6/2006	SYSTEM AND METHOD FOR REDUCING VISUAL ARTIFACTS IN DISPLAYS	QCO.126A	051029
11/669074	1/30/2007	SYSTEMS AND METHODS OF PROVIDING A LIGHT GUIDING LAYER	QCO.129A	061011
11/646059	12/27/2006	ALUMINUM FLUORIDE FILMS FOR MICROELECTROMECHANICAL SYSTEM APPLICATIONS	QCO.130A	061401
11/613922	12/20/2006	MEMS DEVICE AND INTERCONNECTS FOR SAME	QCO.144A	061559
11/313436	12/20/2005	METHOD AND APPARATUS FOR REDUCING BACK-GLASS DEFLECTION IN AN INTERFEROMETRIC MODULATOR DISPLAY	QCO.184A	051137
11/357702	2/17/2006	METHOD AND APPARATUS FOR PROVIDING BACK-LIGHTING IN AN INTERFEROMETRIC MODULATOR DISPLAY DEVICE	QCO.185A	050976
11/406753	4/21/2006	METHOD AND APPARATUS FOR PROVIDING BRIGHTNESS CONTROL IN AN INTERFEROMETRIC MODULATOR (IMOD) DISPLAY	QCO.186A	050636
11/472,879	6/26/2006	LINEAR SOLID STATE ILLUMINATOR	QCO.187A	060040
11/588947	10/27/2006	LIGHT GUIDE INCLUDING OPTICAL SCATTERING ELEMENTS AND A METHOD OF MANUFACTURE	QCO.188A	051339
11/683787	3/8/2007	METHOD AND APPARATUS FOR PROVIDING A LIGHT ABSORBING MASK IN AN INTERFEROMETRIC MODULATOR DISPLAY	QCO.189A	061431

### ASSIGNMENT

WHEREAS, QUALCOMM MEMS Technologies, Inc., a Delaware corporation having offices at 5775 Morehouse Drive, San Diego, California 92121 U.S.A. (hereinafter "ASSIGNOR"), represents and warrants that it is the sole owner of the entire right, title, and interest to certain new and useful improvements for which ASSIGNOR has issued Letters Patents and applications for Letters Patents in the United States (hereinafter "the Patents and Patent Applications") identified in the list attached hereto as Exhibit A;

WHEREAS, QUALCOMM Incorporated, a Delaware corporation having offices at 5775 Morehouse Drive, San Diego, California 92121 U.S.A. (hereinafter "ASSIGNEE") desires to acquire the entire right, title, and interest in and to said improvements and said Patents and Patent Applications;

NOW, THEREFORE, in consideration of One Dollar (\$1.00) to ASSIGNOR, and other good and valuable consideration, the receipt of which is hereby acknowledged, ASSIGNOR hereby further acknowledges that it has sold, assigned, and transferred, and by these presents does hereby sell, assign, and transfer, unto ASSIGNEE, its successors, legal representatives, and assigns, the entire right, title, and interest throughout the world in, to, and under the said improvements, the said Patents and Patent Applications, all Patents that may be granted thereon, all provisional applications relating thereto, and all divisions, continuations, reissues, reexaminations, renewals, and extensions thereof, and all rights of priority under International Conventions and applications for Letters Patent that may hereafter be filed for said improvements or for the said Patents and Patent Applications in any country or countries foreign to the United States; and ASSIGNOR hereby authorizes and requests the Commissioner of Patents of the United States, and any Official of any country foreign to the United States, whose duty it is to issue patents on applications as aforesaid, to issue all Letters Patents for said improvements and all Letters Patents resulting from the Patents and Patent Applications to ASSIGNEE, its successors, legal representatives, and assigns, in accordance with the terms of this Agreement.

ASSIGNOR does hereby sell, assign, transfer, and convey to ASSIGNEE, its successors, legal representatives, and assigns all claims for damages and all remedies arising out of any violation of the rights assigned hereby that may have accrued prior to the date of assignment to ASSIGNEE, or may accrue hereafter, including, but not limited to, the right to sue for, collect, and retain damages for past infringements of the Letters Patents before or after issuance;

ASSIGNOR hereby covenants and agrees that it will communicate to ASSIGNEE, its successors, legal representatives, and assigns any facts known to ASSIGNOR respecting the Patents and Patent Applications immediately upon becoming aware of those facts, and that it will testify in any legal proceeding involving any of the Patents and Patent Applications, will sign all lawful papers, execute all divisional, continuing, and reissue applications, make all rightful oaths, and will generally do everything possible to aid ASSIGNEE, its successors, legal representatives, and assigns to obtain and enforce the Patents and Patent Applications in all countries.



IN TESTIMONY WHEREOF, I hereunto set my hand and seal this 23rd day of May, 2007

QUALCOMM MEMS Technologies, Inc.

By: [Signature]

Name Printed: Clarence Chui

Title: VP, Technology

Date: 5/23/07

IN TESTIMONY WHEREOF, acknowledged hereunto this \_\_\_\_ day of \_\_\_\_\_, 20\_\_.

QUALCOMM Incorporated

By: [Signature]

Name Printed: Phillip P. Lee

Title: Patent Counsel

Date: 6/1/07

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